

U.S. Patent Application Serial No. 09/768,173

Response dated August 29, 2003

Reply to OA of April 7, 2003

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AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claim 1 has been amended as follows:

Listing of Claims:

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Claim 1 (Currently Amended): A chuck equipment comprising
a plate-shaped base,
a first electrode to which a first voltage is applied, and
a second electrode to which a second voltage different from the first voltage in magnitude
is applied, the first and second electrodes being insulated from each other and arranged on a surface
of said base, said first and second electrodes having a substrate thereabove and said substrate is
disposed in an electric field formed between said first and second electrodes, when said first and
second voltages are applied, for holding said substrate onto said first and second electrodes.

Claim 2 (Original): The chuck equipment according to claim 1, wherein said surfaces of said
first and second electrodes are exposed.

Claim 3 (Original): The chuck equipment according to claim 2, wherein the chuck equipment
is constructed in such a manner that a substrate is placed on the surface of said chuck equipment on
which said first and second electrodes are arranged to cause said substrate to be brought into contact
with said first and second electrodes.

Claim 4 (Original): The chuck equipment according to claim 2, wherein the surface of said base is flush with the surfaces of said first and second electrodes.

Claim 5 (Original): The chuck equipment according to claim 2, wherein an insulating convexity portion is arranged between said first and second electrodes.

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Claim 6 (Original): The chuck equipment according to claim 2, wherein said first and second electrodes have a protective film on the surfaces thereof and said protective film is exposed.

Claim 7 (Original): The chuck equipment according to claim 6, wherein the chuck equipment is constructed in such a manner that a substrate is placed on the surface of said chuck equipment on which said first and second electrodes are arranged to cause said substrate to be brought into contact with said protective film formed on said first and second electrodes.

Claim 8 (Original): The chuck equipment according to claim 2, wherein said first electrode is spaced apart from said second electrode by 2mm or less.

Claim 9 (Original): The chuck equipment according to claim 2, wherein said first and second electrodes are 4mm or less in width.

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Claim 10 (Original): The chuck equipment according to claim 2, comprising a plurality of said first and second electrodes arranged thereon, wherein region where said first and second electrodes are alternately arranged is provided.

a¹ Claim 11 (Original): The chuck equipment according to claim 2, comprising a third electrode to which a third voltage different from said first and second voltages is applied.

Claim 12 (Original): A vacuum processing apparatus comprising a vacuum chamber in which the chuck equipment according to claim 2 is arranged.

Claim 13 (Original): The vacuum processing apparatus according to claim 12, comprising a power supply for establishing an electric field of $1.0 \times 10^6 \text{v/m}$ or greater between said first and second electrodes.

Claim 14 (Original): The vacuum processing apparatus according to claim 13, wherein a protective plate is arranged around said chuck equipment, and the vacuum processing apparatus is constructed in such a manner that a substrate is placed on said chuck equipment to cause said substrate to be accommodated in said protective plate.